

(c) Amendment to the Claims

Please amend claim 12 as follows. The status of all the claims is listed below.

Claims 1. - 11. (Cancelled)

12. (Currently Amended) A plasma treatment apparatus comprising:
a plurality of movable reactors each having an evacuable interior
where at least one treatment substrate is set, and having impedances different from each
other;
a high-frequency power supply means for supplying high-frequency
power into each movable reactor having been internally-evacuated, to cause glow discharge
to take place in the movable reactor ~~wherein each of the reactors and the high-frequency~~
~~power supply means are provided separately;~~
~~a plurality of an impedance regulation means provided~~
~~correspondingly to the impedances of each of the reactors in order to regulate impedance~~
~~spaced in impedances on the side of each movable reactor and in on the side of the high-~~
frequency power supply means; and
a moving means for moving each of the movable reactors,
wherein each of the movable reactors and the high-frequency power
supply means are provided separately and wherein the impedance regulation means are
provided on the side of each movable reactor.

13. (Previously Presented) The plasma treatment apparatus of claim 12,
wherein the substrate is a substrate for an electrophotographic photosensitive member.

14. - 25. (Cancelled)